## DOE laser beam shaping at XFEL

On the Generation of Spatial Flat-Top Laser Spots
and the Influence of Optical Errors on the Beam Dynamics

## DESY/TEMF Meeting, Spring 2018

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Optical Setup:
Steffen Schmid (TEMF), Sebastian Pumpe (DESY)
Beam Simulations:
Martin Dohlus (DESY)

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## Optical Setup

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## Laser Beam of the XFEL-Photogun

## PITZ / XFEL-Photogun


(Image source: R. Martin, Master thesis, Institute of Physics, HU Berlin, 2013)

## Spatial Laser Spot Profile


(Image source: M. Krasilnikov, et al., FEL2013, New York)
$\Rightarrow$ Spatial flat-top profile of laser spot on cathode needed

## Two Possibilities:

"Old": Beam Shaping Aperture (BSA)
"New": Diffractive Optical Elements (DOE)

## "OId Method" - BSA

## ( $\equiv$ Optical Imaging of an Aperture)



+ Robust against deviations of input beam quality
- Sophisticated imaging system needed
- Smaller spot sizes require larger optics
- 98\% of laser intensity gets lost ( leads to further problems )


## "New Method" - DOE

## (三 Spatial Phase Modulation of Gaussian Laser Beam)



Optical lens transfer function:
$g_{o}\left(x_{0}, y_{o}\right)=e^{i \pi \frac{\left(x_{0}^{2}+y_{0}^{2}\right)}{\lambda f}\left(1-\frac{z}{f}\right) \cdots}$
$\cdots \iint g_{i}\left(x_{i}, y_{i}\right) e^{-\frac{2 \pi i}{\lambda f}\left(x_{0} \cdot x_{i}+y_{o} \cdot y_{i}\right)} d x_{i} d y_{i}$
$\Rightarrow$ Fourier Transformation
(Formula: MIT 2.71/2.710 04/08/09 wk9-b-18 )

## "New Method" - DOE

## (三 Spatial Phase Modulation of Gaussian Laser Beam)



## "New Method" - DOE

## (三 Spatial Phase Modulation of Gaussian Laser Beam)



+ "Simple" imaging system
+ Smaller spot sizes ( $<\mathbf{5 0} \boldsymbol{\mu m}$ ) possible
+ Only ~3\% of laser intensity gets lost ( increases setup stability )


## - Sensitive on input beam quality

## BSA and DOE spatial shaping at XFEL



## Wavelength dependence of DOE

XFEL Laser 1: 257 nm<br>XFEL Laser 2: 266 nm

measured (266 nm)


## DOE designed

for 257 nm




Measured transverse Profiles und Ideal Pencil Profiles

DOE

C_20180421_171716


$$
\frac{\sigma_{x}}{\sigma_{z}}=1.19
$$

$$
\sqrt{\sigma_{x} \sigma_{y}}=0.256 \mathrm{~mm}
$$

DESY. Slide by Martin Dohlus

$$
\rightarrow \text { pencil } 1
$$

## C_20180422_135931

${ }^{-3} \mathbf{x s t d} / \mathrm{mm}=0.29539 \mathrm{ystd} / \mathrm{mm}=0.24957$


$$
\begin{aligned}
& \frac{\sigma_{x}}{\sigma_{z}}=1.18 \\
& \sqrt{\sigma_{x} \sigma_{y}}=0.272 \mathrm{~mm}
\end{aligned}
$$

$\rightarrow$ pencil 2

Measured transverse Profiles and Ideal Pencil Profiles


## Summary: Optical Setup

- Laser output to cathode transmission efficiency $T$ increased
$\Rightarrow \quad$ Beam Shaping Aperture (BSA): $\quad T=10 \%$
Diffractive Optical Element (DOE): $\quad T=94 \%$
$\Rightarrow$ Investigate long-term stability of DOE system
- Laser used for measurements $(266 n m) \neq$ DOE design ( 257 nm )
$\Rightarrow \quad$ Clipped $0^{\text {th }}$ order peak in DOE spot intensity map
$\Rightarrow \quad$ Repeat measurements with $\lambda_{\text {laser }}=257 \mathrm{~nm}$
- BSA \& DOE laser spots are both elliptical
$\Rightarrow \quad$ Effect of optics downstream of beam shaping setup


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## Beam Simulations

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## Gun Simulation with Krack

Krack is an implementation of a Poisson solver (approach 2 or EB-method); it uses binning of the charge to an equidistant grid and the convolution with a kernel function (charged cuboids)
the start distribution is Gaussian in time ( 6.65 psec rms ) and according to the measured profiles in the transverse dimension; simulations have been done with $250 \mathrm{pC}, 400 \mathrm{pC}$ and 500 pC with 1E6 particles
the transverse resolution is $0.07 \sigma_{t}$; all external fields (gun, solenoid and 8 tesla cavities) have rz-symmetry; the distribution is tracked from the cathode to the exit of the last cavity of ACC1;
the injection is calculated with 500 time steps and a longitudinal resolution better than $10 \mu \mathrm{~m}$ by a $2^{\text {nd }}$ order RK-integrator; the rest is calculated with a longitudinal resolution of $0.05 \sigma_{z}$ by a $5^{\text {th }}$ order RK-integrator
the gun-phase and solenoid strength are optimized for minimal projected emittance after ACC1; criterion $\varepsilon_{x, n} \varepsilon_{\chi, n}=$ min

Overview: Simulation of 250 pC from Cathode through ACC1 to $\mathrm{Z}=14.2 \mathrm{~m}$


pencil 1 (sigma $=0.256 \mathrm{~mm}$ )
$B_{\text {sol }}=0.2050 \mathrm{~T} \varphi=\varphi_{0}-2.0 \mathrm{deg}$
$Q=250 \mathrm{pC} \quad \mathrm{I}_{\text {peak }}=13.93 \mathrm{~A}$
$\alpha_{x}=-5.40 \quad \alpha_{y}=-5.61$
$\beta_{x}=53.1 \mathrm{~m} \quad \beta_{y}=54.1 \mathrm{~m}$
$\varepsilon_{\mathrm{x}, \mathrm{p}}=0.614 \mu \mathrm{~m} \quad \varepsilon_{\mathrm{y}, \mathrm{p}}=0.612 \mu \mathrm{~m}$
$\varepsilon_{\mathrm{x}, \mathrm{s}}=0.375 \mu \mathrm{~m} \quad \varepsilon_{\mathrm{y}, \mathrm{s}}=0.375 \mu \mathrm{~m}$
pencil 2 (sigma $=0.272 \mathrm{~mm}$ )
$B_{\text {sol }}=0.2050 \mathrm{~T} \varphi=\varphi_{0}-2.0 \mathrm{deg}$
$Q=250 \mathrm{pC} \quad \mathrm{I}_{\text {peak }}=14.14 \mathrm{~A}$
$\alpha_{x}=-4.77 \quad \alpha_{y}=-4.69$
$\beta_{x}=43.0 \mathrm{~m} \quad \beta_{\mathrm{y}}=42.4 \mathrm{~m}$
$\varepsilon_{\mathrm{x}, \mathrm{p}}=0.647 \mu \mathrm{~m} \quad \varepsilon_{\mathrm{y}, \mathrm{p}}=0.647 \mu \mathrm{~m}$
$\varepsilon_{\mathrm{x}, \mathrm{s}}=0.38 \quad \mu \mathrm{~m} \quad \varepsilon_{\mathrm{y}, \mathrm{s}}=0.38 \quad \mu \mathrm{~m}$

Overview: Simulation of 400 pC from Cathode through ACC1 to $\mathrm{Z}=14.2 \mathrm{~m}$


pencil 1 (sigma $=0.256 \mathrm{~mm}$ )
$\mathrm{B}_{\text {sol }}=0.2055 \mathrm{~T} \varphi=\varphi_{0}-3.0 \mathrm{~d}$
$\mathrm{B}_{\text {sol }}=0.2055 \mathrm{~T} \varphi=\varphi_{0}-3.0 \mathrm{deg}$
$Q=400 \mathrm{pC} \quad \mathrm{I}_{\text {peak }}=19.36 \mathrm{~A}$
$\alpha_{x}=-3.23 \quad \alpha_{y}=-3.31$
$\beta_{x}=36.4 \mathrm{~m} \quad \beta_{y}=37.5 \mathrm{~m}$
$\varepsilon_{\mathrm{x}, \mathrm{p}}=0.629 \mu \mathrm{~m} \quad \varepsilon_{\mathrm{y}, \mathrm{p}}=0.632 \mu \mathrm{~m}$
$\varepsilon_{\mathrm{x}, \mathrm{s}}=0.51 \mu \mathrm{~m} \quad \varepsilon_{\mathrm{y}, \mathrm{s}}=0.51 \mu \mathrm{~m}$
pencil 2 (sigma $=0.272 \mathrm{~mm}$ )
$\mathrm{B}_{\text {sol }}=0.2057 \mathrm{~T} \varphi=\varphi_{0}-2.5 \mathrm{deg}$
$Q=400 \mathrm{pC} \quad \mathrm{I}_{\text {peak }}=19.88 \mathrm{~A}$
$\alpha_{x}=-2.62 \quad \alpha_{y}=-2.49$
$\beta_{x}=28.3 \mathrm{~m} \quad \beta_{y}=27.0 \mathrm{~m}$
$\varepsilon_{x, p}=0.653 \mu \mathrm{~m} \quad \varepsilon_{y, p}=0.656 \mu \mathrm{~m}$
$\varepsilon_{x, \mathrm{~s}}=0.50 \quad \mu \mathrm{~m} \quad \varepsilon_{\mathrm{y}, \mathrm{s}}=0.50 \quad \mu \mathrm{~m}$

Overview: Simulation of 500 pC from Cathode through ACC1 to $\mathrm{Z}=14.2 \mathrm{~m}$

projected/slice emittance slice properties at $z\left(I_{\text {peak }}\right)$

A Figure of Merit
$\underset{\text { (assuming optimal beta function) }}{\text { power gain length }} L_{g}=1.18 \sqrt{\frac{I_{A}}{I_{\text {paak }}}} \frac{\left(\varepsilon_{n} \lambda_{w}\right)^{5 / 6}}{\lambda_{\gamma}^{2 / 3}} \frac{\left(1+\frac{K^{2}}{2}\right)^{1 / 3}}{K A_{J J}}\left(1+\delta\left(\sigma_{\gamma}, \mathrm{L}\right)\right)$

$$
f=\frac{\left(\varepsilon_{x, s} \varepsilon_{y, s}\right)^{5 / 12}}{\sqrt{I_{\text {peak }}}} \frac{\sqrt{\mathrm{A}}}{(\mu \mathrm{~m})^{5 / 6}}
$$

250 pC

| C_20180421 (DOE) f $=$ | 0.2038 |
| :--- | :--- |
| C_20180422 (BSA) | 0.1729 |
| pencil_1 | 0.1183 |
| pencil_2 | 0.1181 |

400 pC C_20180421 (DOE) f=
0.1830 C_20180422 (BSA)
0.1685 pencil_1
0.1297
pencil_2
0.1267

```
500 pC C_20180421 (DOE) f=
0.1808 C_20180422 (BSA)
0.1711 pencil_1
0.1606
pencil_2
0.1508
```


## Summary/Conclusion: Gun Simulations

simulation for 250pC: pencil emittances < BSA emittances < DOE emittances;
this is more pronounced for slice emittances $\rightarrow$ there is a lot to gain by a flat profile
simulation for 500pC: saturation effects, differences in emittance are less significant
figure of merit based on gain length prefers flat beams with lower charge

## Summary/Conclusion

DOE measurements have been done with laser 2 (266 nm); the measured profile is not flat; better results are expected for laser 1 (257 nm);
measured DOE profile is clipped
BSA \& DOE beams are not round $\rightarrow$ it is not possible to optimize both foci simultaneously
simulation for 250pC: pencil emittances < BSA emittances < DOE emittances;
this is more pronounced for slice emittances $\rightarrow$ there is a lot to gain by a flat profile
simulation for 500 pC : saturation effects, differences in emittance are less significant
figure of merit based on gain length prefers flat beams with lower charge
DOE measurements with laser 1 are planned

